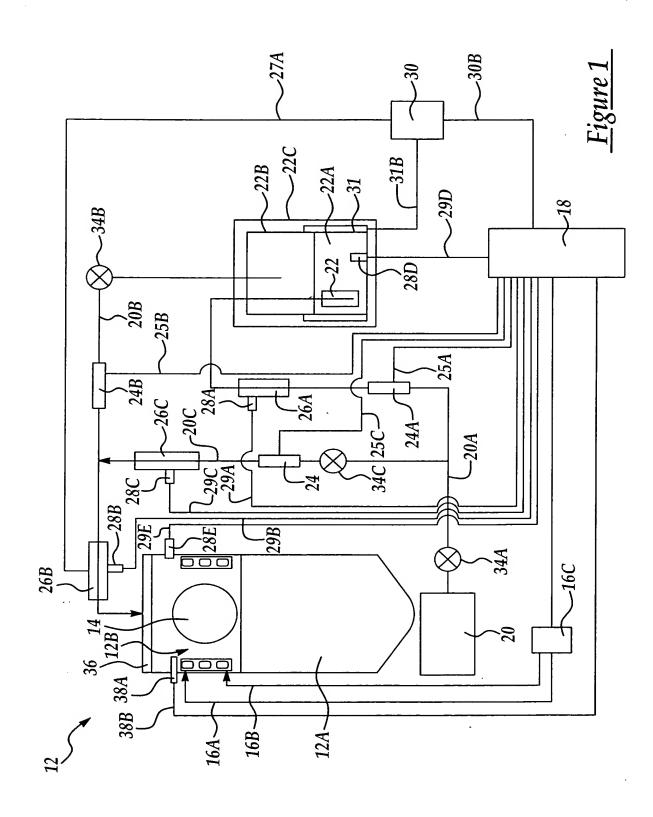
1/2

Inventor: Jia-Ren Chen Serial No.: To Be Assigned Filed: Herewith

For: Method to Improve Post Wafer Etch Cleaning Process

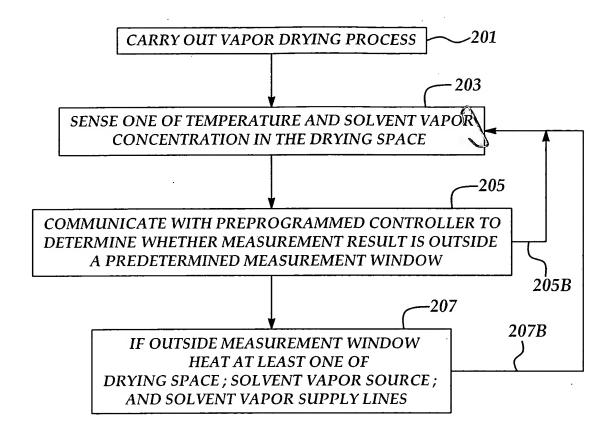
Attorney Doc. No.: 67,200-1121



Serial No.: To Be Assigned Filed: Herewith For: Method to Improve Post Wafer Etch Cleaning Process

Attorney Doc. No.: 67,200-1121

2/2



<u>Figure 2</u>